		Sheet	t 1 of 2	<u> </u>
Form 1449*	Atty. Docket No.: 303.684US3	Serial No. Unknown	PTO	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Applicant: Leonard Forbes		s. 306	
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77	C DAMENT DOCUMENTS			

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^{**}EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

5	sheet 2 of 2
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